

LISTING OF THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the application:

1. **(Currently Amended)** A substrate processing apparatus supplying a fluid to a rotated substrate for performing prescribed processing, comprising:

a substrate holding/rotating element holding and rotating said substrate; and

an atmosphere blocking member, corresponding in planar shape and size to said substrate, arranged oppositely and proximately to at least one surface of said substrate held by said substrate holding/rotating element and formed with a processing solution discharge port and a single inner gas discharge port discharging a processing solution and gas to said surface of said substrate respectively, wherein

said single inner gas discharge port is arranged eccentrically to a center of said surface of said substrate held by said substrate holding/rotating element, and

an outer gas discharge port is formed on said atmosphere blocking member outside said single inner gas discharge port so as to continuously and annularly enclose said single inner gas discharge port in plan view for discharging gas to said surface of said substrate held by said substrate holding/rotating element.

2. **(Canceled)**

3. **(Currently Amended)** The substrate processing apparatus according to claim [[21]] 1, wherein

said outer gas discharge port is so formed on said atmosphere blocking member that [[said]] an arrival position of said gas discharged from said outer gas discharge port is in the vicinity of said intermediate portion between the center and the outer peripheral edge of said surface of said substrate held by said substrate holding/rotating element.

4. **(Currently Amended)** The substrate processing apparatus according to claim 3, wherein